

UNITED STATES PATENT AND TRADEMARK OFFICE
CERTIFICATE OF CORRECTION

PATENT NO. : 7,053,001 B2
APPLICATION NO. : 10/676983
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INVENTOR(S) : Tingkai Li et al.

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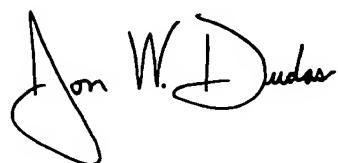
It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Column 5, line 29 insert the following:

15. The method of claim 7 wherein the etching chamber pressure is maintained at a pressure of about 6 mtorr; and wherein BCl is delivered at a flow rate of about 30 sccm, and Cl is delivered at a flow rate of about 60 sccm, providing a gas volume of Cl which is twice that of BCl.

Signed and Sealed this

Nineteenth Day of February, 2008



JON W. DUDAS
Director of the United States Patent and Trademark Office